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To: Commissioner for Patents
Art Unit 2813

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From: Ira Matsil

Pages: 9Applicant: Chen, *et al.*

Docket No: 01 P 11914 US

Serial No.: 09/965,093

Art Unit: 2856

Filed: September 28, 2001

Examiner: Raevis, Robert R.

For: Direct, Non-Destructive Measurement of Recess Depth in a Wafer

Certificate of Transmission under 37 C.F.R. § 1.8

I hereby certify that the following correspondence is being facsimile transmitted to the Patent and Trademark Office on October 8, 2003.

Facsimile Cover Sheet with Certificate of Transmission (1 page)
Amendment (8 pages)

Signature


Julie Russell

Name of Person Signing the Certificate

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Chen, *et al.*

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Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

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RESPONSE UNDER 37 CFR 1.111

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Dear Sir:

In response to the Office Action of July 11, 2003, please amend this application as follows: